

2
PATENTS
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Casimer M. DeCusatis, et al.

Docket: FIS920010130US1(14563)

Serial No.: Unassigned

Dated: September 20, 2001

Filed: Herewith

For: REAL-TIME PROCESS CONTROL FOR
OPTICAL COMPONENT FABRICATION

Assistant Commissioner for Patents
Washington, DC 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §§1.56, 1.97 and 1.98, applicants submit the following references which applicants believe may be material to the above-identified patent application. A copy of the references which applicants wish to make of record in this case is enclosed herein for the Examiner's convenience along with a listing on Form PTO-1449 attached.

1. Bann, R., et al., "Micromachining system accommodates large wafers," Laser Focus World, www.optoelectronics-world.com, pp. 189-192, January 2001;

2. Kartalopoulos, S., "INTRODUCTION TO DWDM TECHNOLOGY Data in a Rainbow," IEEE, Chapter 3, pp. 67-68, (1999); and

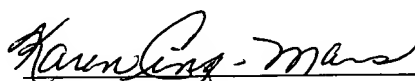
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Dated: October 12, 2001



Karen Cing-ars

3. Carroll, J., et al., "Distributed feedback semiconductor lasers," IEEE Circuits, Devices and Systems Series 10, SPIE Press Monograph, Vol. PM52, pp 9-15, (1998).

All the references listed on Form PTO-1449 are in the English language, thus, a concise explanation of those references required by 37 C.F.R. §1.98(a)(3) is not necessary.

This Information Disclosure Statement is being submitted with the filing of this application; thus no fee or certification under 37 C.F.R. §1.97(e) is required.

Respectfully submitted,


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INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional)

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Group Art Unit

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*EXAMINER
INITIAL

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Bann, R., et al., "Micromachining system accommodates large wafers," Laser Focus World, www.optoelectronics-world.com, pp. 189-192, January 2001

Kartalopoulos, S., "INTRODUCTION TO DWDM TECHNOLOGY Data in a Rainbow," IEEE, Chapter 3, pp. 67-68, (1999)

Carroll, J., et al., "Distributed feedback semiconductor lasers," IEE Circuits, Devices and Systems Series 10, SPIE Press Monograph, Vol. PM52, pp 9-15, (1998)

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.